

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Pablo I. Rovira  
Assignee: Nanometrics Incorporated  
Title: Optical Metrology System with Combined Interferometer and Ellipsometer  
Serial No.: 10/016,943 Filing Date: December 13, 2001  
Examiner: Samual A. Turner Group Art Unit: 2877  
Docket No.: NAN051 US Confirmation No.: 7400

Mail Stop Non-Fee Amendment  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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NOV 10 2003  
AC 1700  
Santa Clara, California  
October 31, 2003

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CHNOLGY CENTER 2800

RESPONSE TO OFFICE ACTION

Dear Sir:

This Response to Office Action is responsive to the August 20, 2003, Office Action, which has a statutorily shortened period for response that ends November 20, 2003. Please enter the following amendments before taking action on the merits of the above-referenced application.

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